

Also, a microlithographic reduction projectin catadioptric objective is known to those skilled in the art to image a first object, namely a reticle, to a second object, namely to a wafer, at a definite distance, typically on the order of magnitude of 1 m. In contrast, the object-image distance of binoculars typically is greater by one or more orders of magnitude.

Applicants respectfully submit the present amendment should be entered since it does not require additional searching and/or consideration by the Examiner. The present amendment to claim 2 merely more positively recites an element that the Examiner has previously been exposed to and has already considered. Since, the present amendment places the application in condition for allowance and does not require further consideration and/or searching by the Examiner, the present amendment should be entered.

While the Examiner has objected to claim 31, Applicants believe this is in error since claim 31 depends from claim 6 which stands allowed as opposed to depending from rejected claim 2. Withdrawal of this objection is in order.

In view of the above, each of the presently pending claims in this application is believed to be in immediate condition for allowance. Accordingly, the Examiner is respectfully requested to pass this application to issue.

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Respectfully submitted,

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